

## PATENT ASSIGNMENT

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SUBMISSION TYPE:	NEW ASSIGNMENT										
NATURE OF CONVEYANCE:	ASSIGNMENT										
CONVEYING PARTY DATA											
<table border="1"><thead><tr><th>Name</th><th>Execution Date</th></tr></thead><tbody><tr><td>SHIFANG LI</td><td>09/13/2007</td></tr><tr><td>HANYOU CHU</td><td>09/17/2007</td></tr></tbody></table>		Name	Execution Date	SHIFANG LI	09/13/2007	HANYOU CHU	09/17/2007				
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RECEIVING PARTY DATA											
<table border="1"><tr><td>Name:</td><td>Tokyo Electron Limited</td></tr><tr><td>Street Address:</td><td>3-6 Akasaka 5-chome</td></tr><tr><td>City:</td><td>Minato-Ku Tokyo</td></tr><tr><td>State/Country:</td><td>JAPAN</td></tr><tr><td>Postal Code:</td><td>107-8481</td></tr></table>		Name:	Tokyo Electron Limited	Street Address:	3-6 Akasaka 5-chome	City:	Minato-Ku Tokyo	State/Country:	JAPAN	Postal Code:	107-8481
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PROPERTY NUMBERS Total: 1											
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CORRESPONDENCE DATA											
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PATENT  
REEL: 019856 FRAME: 0819

ASSIGNMENT OF INVENTION AND PATENTS THEREON

For valuable consideration, I/we, **SHIFANG LI**, hereby assign to Tokyo Electron Limited, a Corporation of Japan and having a place of business at TBS Broadcast Center, 3-6 Akasaka 5-chome, Minato-Ku, Tokyo 107-8481 JAPAN, and its successors and assigns (collectively hereinafter called "the Assignee"), my entire right, title and interest throughout the world in the inventions and improvements which are subject of an application of United States Patent entitled **DETERMINING PROFILE PARAMETERS OF A STRUCTURE FORMED ON A SEMICONDUCTOR WAFER USING A DISPERSION FUNCTION RELATING PROCESS PARAMETER TO DISPERSION**, and filed on September 20, 2007 as Patent Application No.

11 858 882, preparatory to obtaining Letters Patent of the United States therefore, this assignment including said application, any continuation, division or continuation-in-part thereof and/or substituted therefore, any and all United States and foreign patents, utility models, and design registrations granted for any of said inventions or improvements, and the right to claim priority based on the filing date of said application under the International Convention for the Protection of Industrial Property, the Patent Cooperation Treaty, the European Patent Convention, and all other treaties of like purposes; and authorize the Assignee to apply in all countries in my name or in its own name for patents, utility models, and design registrations and like rights of exclusion and for inventors' certificates for said inventions and improvements; and agree for myself and my heirs, legal representatives and assigns, without further compensation to perform such lawful acts and to sign such further applications, assignments, Preliminary Statements and other lawful documents as the Assignee may reasonably request to effectuate fully this Assignment. I hereby authorize and request that any one of the attorneys or agents of Tokyo Electron U.S. Holdings, 2400 Grove Boulevard, Austin, Texas 78741, to insert herein the filing date and application serial number of said application when known.

Inventor's Signature: Shifang Li Date: 9/13/07  
Full Name: SHIFANG LI  
Residence: 5043 Rigatti Circle, Pleasanton, CA 94588

ASSIGNMENT OF INVENTION AND PATENTS THEREON

For valuable consideration, I/we, **HANYOU CHU**, hereby assign to Tokyo Electron Limited, a Corporation of Japan and having a place of business at TBS Broadcast Center, 3-6 Akasaka 5-chome, Minato-Ku, Tokyo 107-8481 JAPAN, and its successors and assigns (collectively hereinafter called "the Assignee"), my entire right, title and interest throughout the world in the inventions and improvements which are subject of an application of United States Patent entitled **DETERMINING PROFILE PARAMETERS OF A STRUCTURE FORMED ON A SEMICONDUCTOR WAFER USING A DISPERSION FUNCTION RELATING PROCESS PARAMETER TO DISPERSION**, and filed on September 20, 2007 as Patent Application No.

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Inventor's Signature: \_\_\_\_\_

Date: \_\_\_\_\_

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TTI-177

PATENT

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